



Rardchawadee Silapunt

MAJOR DEPT Electrical Engineering
DEGREE PH. D
ADVISOR Prof. Amy E. Wendt
RESEARCH AREA Plasma etching
GRADUATION December 2002

KEY WORDS

Low-k dielectric selective etching through ion energy control

GOALS

To improve etch selectivity of low dielectric constant material (low-k) in interest to etch stop layer material by using developed bias technique. To gain more understanding on surface mechanisms of low-k material and on feature profile control.

INTERESTS

Study about etching characteristics of low-k materials. The etching processes for modern integrated circuit (IC) manufacturing. Modeling of plasma properties during processing.

VISA STATUS

Thai Citizen

ADDRESS

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Rardchawadee Silapunt (continued)

EDUCATION

- | | |
|-------|--|
| 12/02 | PhD (expected) University of Wisconsin-Madison, Electrical Engineering |
| 12/98 | MS University of Wisconsin-Madison, Electrical Engineering |
| 03/96 | BS Chulalongkorn University, Electrical Engineering |

WORK EXPERIENCE

- | | |
|----------------|--|
| 1996 | Advance Info Service Company limited (Bangkok, Thailand)
Department of International Roaming services |
| 1998 | University of Wisconsin-Madison, College of Engineering
Teaching Assistant – Applied Communications System <ul style="list-style-type: none">• Leading tutorial section about Advance Design System software |
| 1999 | University of Wisconsin-Madison, College of Engineering
Research Assistant – Plasma Etching group <ul style="list-style-type: none">• Performing independent research on plasma diagnostics by magnetic probe measurement in ICP source
Teaching Assistant – Applied Communications System <ul style="list-style-type: none">• Leading tutorial section about Advance Design System software• Helping undergraduate students work on design project |
| 2000 - present | University of Wisconsin-Madison, College of Engineering
Research Assistant – Plasma Etching group <ul style="list-style-type: none">• Performing independent research on plasma etching of low dielectric constant material using new bias technique |

LANGUAGES

Fluent in both English and Thai

Rardchawadee Silapunt (continued)

HONORS & AWARDS

- | | |
|------|--|
| 1996 | Member of Engineering Institute of Thailand under H.M.
The King's Patronage |
| 1996 | Ministry of Science and Technology's Scholarship
(Thailand) |

ACTIVITIES & AFFILIATIONS

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|-----------|--|
| 1992-1996 | Chulalongkorn University, Thailand <ul style="list-style-type: none">• Cheerleader of faculty of Engineering |
| 1999-2000 | Director of Sport Activity, Thai Students Association
(TSA) of UW-Madison |